

| Application/Control No. | Applicant(s)/Patent under Reexamination | |
|-------------------------|--|---|
| 10/825,109 | CHEN, MEI-LI | _ |
| Examiner | Art Unit | |
| John Rivell | 3753 | |

John Rivell

| SEARCHED | | | | | |
|----------|---------------------------|-----------|----------|--|--|
| Class | Subclass | Date | Examiner | | |
| 137 | 625.17 625.4 625.41 | 7/10/2006 | R | | |
| | | | | | |
| | | | | | |
| | | | - | | |
| | | | | | |
| | | | - | | |
| | + | | | | |
| | | | | | |
| | | | - | | |
| | | - | - | | |
| | 1 | 1 | 1 | | |

| Class | Subclass | Date | Examine |
|-------|----------|------|---------|
| | | | |
| | | | |
| | 1 | | + |
| | | | |
| | | | |
| | | | |

| SEARCH NOTES (INCLUDING SEARCH STRATEGY) | | | | |
|---|-----------|------|--|--|
| (,,,, | DATE | EXMR | | |
| None | 7/11/2006 | R | | |
| | | | | |
| | | | | |
| | | | | |
| | | | | |
| | | | | |
| | | | | |
| | | | | |